## Heterogeneous integration of SiGe/Ge and III-Vs on Si for electronic-photonic integrated circuits Univ. Tokyo<sup>1</sup>, JST-CREST<sup>2</sup>, °Mitsuru Takenaka<sup>1,2</sup>, Shinichi Takagi<sup>1,2</sup> E-mail: takenaka@mosfet.t.u-tokyo.ac.jp

Heterogeneous integration of SiGe, Ge and III-V semiconductors on Si enables us to integrate photodetectors (PDs), modulators, and laser didoes (LDs) on Si photonics platform. Since SiGe/Ge and III-Vs have high hole and electron mobility, we are also able to integrate monolithically high-performance metal-oxide-semiconductor (MOS) transistors based on those semiconductors. Thus, the heterogeneous integration is a key enabler to realize high-performance and low-power electronic-photonic integrated circuits (EPICs) as shown in Fig. 1. We present our recent developments of EPICs based on SiGe/Ge and III-V integration on Si platform for near and mid-infrared photonics.

We have investigated SiGe-based optical modulators to enhance the modulation efficiency [1]. Strain SiGe is expected to exhibit greater free-carrier effects than Si owing to the light hole effective mass in SiGe. We have successfully demonstrated the enhanced free-carrier absorption and plasma dispersion effect in SiGe by making carrier-injection SiGe optical modulators [2,3].

Ge is an attractive material for mid-infrared photonics because of its transparency. We have proposed Ge CMOS photonics platform on a Ge-on-Insulator (GeOI) wafer [4]. A high-quality GeOI wafer fabricated by wafer bonding enables the first demonstration of Ge strip and rib waveguide on the GeOI for mid-infrared wavelengths. Ge passive components and carrier-injection VOAs have been successfully demonstrated [5].

We have proposed and investigated the III-V CMOS photonics platform [6]. By using a III-V-OI wafer, Siphotonic-like III-V photonic integrated circuits can be developed. We have demonstrated InP-based photonicwire passive components [7,8], carrier-injection modulators [9], and InGaAs PDs [10] on the III-V-OI wafer. In summary, the heterogeneous integration of SiGe/Ge and III-Vs can extend functionalities on Si photonics platform through electronic-photonic integration.

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References: [1] M. Takenaka et al., JQE **100**, 8-15 (2012). [2] Y. Kim et al., Scientific Reports **4**, 7458-7464 (2014). [3] Y. Kim et al., OE **24**, 1979-1985 (2016). [4] J. Kang et al., Materials Science in Semiconductor Processing **42**, 259-263 (2015). [5] J. Kang et al., OE **24**, 11855 (2016). [6] M. Takenaka et al., OE **15**, 8422-8427 (2007). [7] M. Takenaka et al., APEX **2**, 7 (2009). [8] M. Takenaka et al., APEX **6**, 042501 (2013). [9] Y. Ikku et al., OE **20**, B357-B364 (2012). [10] Y. Cheng et al., JJAP **55**, 04EH01 (2016).

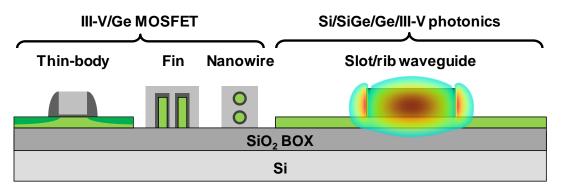


Fig. 1 Electronic-photonic integrated circuits by heterogeneous integration of SiGe/Ge and III-V semiconductors on Si.